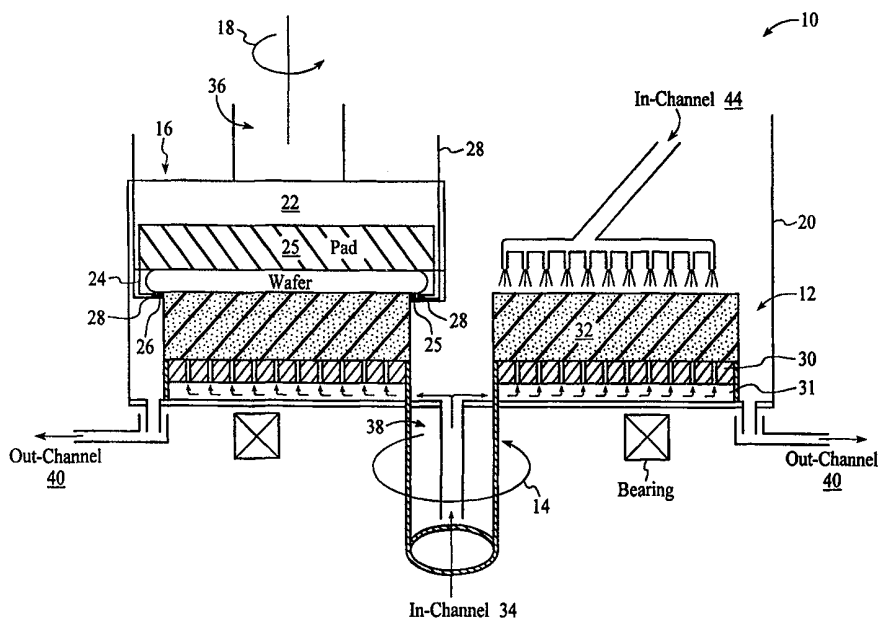




## INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

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**(54) Title:** METHOD AND APPARATUS FOR ELECTROCHEMICAL MECHANICAL DEPOSITION



**(57) Abstract**

The present invention deposits a conductive material from an electrolyte solution to a predetermined area of a wafer. The steps that are used when making this application include applying the conductive material to the predetermined area of the wafer using an electrolyte solution disposed on a surface of the wafer, when the wafer is disposed between a cathode and an anode, and preventing accumulation of the conductive material to areas other than the predetermined area by mechanically polishing the other areas while the conductive material is being applied.

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# INTERNATIONAL SEARCH REPORT

International Application No

PCT/US 99/25656

## A. CLASSIFICATION OF SUBJECT MATTER

IPC 7 C25D5/02 C25D5/22 C25D5/06

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 C25D

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

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WPI Data, PAJ, INSPEC

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
E	<p>US 6 004 880 A (LIU YAUH-CHING ET AL) 21 December 1999 (1999-12-21)</p> <p>column 3, line 61 - line 64 column 4, line 53 - line 67 column 5, line 63 - column 6, line 14 claims 1,3-5,12,14</p> <p>---</p> <p>-/--</p>	<p>1-3, 8-15, 18, 19, 21-24, 41-45, 47-51, 53-56, 58,61-65</p>



Further documents are listed in the continuation of box C.



Patent family members are listed in annex.

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

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International Application No

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## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category °	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	<p>DE 43 24 330 A (ATOTECH DEUTSCHLAND GMBH) 3 February 1994 (1994-02-03)</p> <p>abstract column 2, line 37 - line 60 column 4, line 16 - line 24 claims 1,2 figure 1</p> <p>-----</p>	<p>1,8, 10-15, 50,51, 54,61,62</p>

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information on patent family members

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